

U.S. Department of Commerce, Patent and Trademark Office		Docket No.	Serial No.
(PTO Form 1449 modified)		5625/D01/JB	10/731,651
SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT		Applicant	Confirmation No.:
		Lu, et al.	Unknown
(Use several sheets if necessary)		Filing Date	Group
Examiner Unknown		December 9, 2003	Unknown

## U.S. Patent Documents

*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
AS	A1	4,813,846	03/21/89	Helms	414	744.1	04/29/87
	A2	4,917,556	04/17/90	Stark et al.	414	217	05/26/89
	A3	4,951,601	08/28/90	Maydan, et al.	118	719	06/23/89
	A4	5,000,113	03/19/91	Wang et al.	118	723	12/19/86
	A5	5,028,565	07/02/1991	Chang, et al.	437	192	08/25/1989
	A6	5,173,474	12/22/1992	Connell, et al.	505	1	03/11/1991
	A7	5,186,718	02/16/93	Tepman et al.	29	25.01	04/15/91
	A8	5,205,077	04/27/93	Wittstock	51	165 R	08/28/91
	A9	5,234,561	08/10/93	Randhawa et al.	204	192.38	08/25/88
	A10	5,259,881	11/09/93	Edwards, et al.	118	719	05/17/91
	A11	5,286,296	02/15/94	Sato et al.	118	719	01/09/92
	A12	5,580,380	12/03/1996	Liu, et al.	117	86	01/30/1995
	A13	5,609,689	03/11/97	Kato et al.	118	719	06/03/96
	A14	5,667,592	09/16/97	Boitnott et al.	118	719	04/16/96
	A15	5,674,786	10/07/97	Turner et al.	437	225	06/05/95
	A16	5,695,564	12/09/97	Imahashi	118	719	08/03/95
	A17	5,730,801	03/24/98	Tepman et al.	118	719	08/23/94
	A18	5,788,447	08/04/98	Yonemitsu et al.	414	217	08/05/96
	A19	5,788,799	08/04/98	Steger, et al.	156	345	06/11/96
	A20	5,801,634	09/01/98	Young et al.	340	635	09/08/97
	A21	5,856,219	01/05/99	Naito et al.	438	241	08/18/97
	A22	5,866,213	02/02/99	Foster et al.	427	573	07/19/97
	A23	5,866,795	02/02/99	Wang et al.	73	1.36	03/17/97
	A24	5,882,165	03/16/99	Maydan et al.	414	217	09/10/97
	A25	5,882,413	03/16/99	Beaulieu et al.	118	719	07/11/97
	A26	5,928,389	07/27/99	Jevtic	29	25.01	10/21/96

Examiner

Date Considered

11/20/06

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## U.S. Patent Documents

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21/29/06

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## Foreign Patent Documents

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
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Examiner <i>Ande Stenro</i>	Date Considered <i>11/29/06</i>
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Examiner <i>Andrew Evans</i>					Date Considered <i>11/20/06</i>			
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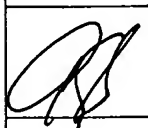
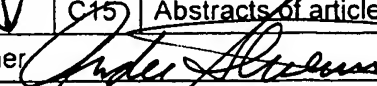
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(PTO Form 1449 modified)		5625/D01/JB	10/731,651
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	C2	Scheper, et al., "Low-temperature deposition of titanium nitride films from dialkylhydrazine-based precursors", Materials Science in Semiconductor Processing 2 (1999), pp. 149-157	
	C3	Suzuki, et al., "A 0.2-μm contact filing by 450°C-hydrazine-reduced TiN film with low resistivity", IEDM 92-979, pp. 11.8.1 – 11.8.3	
	C4	Suzuki, et al., "LPCVD-TiN Using Hydrazine and TiCl <sub>4</sub> ", VMIC Conference (June 8-9, 1993), pp. 418-423	
	C5	IBM Tech. Disc. Bull. "Knowledge-Based Dynamic Scheduler in Distributed Computer Control, (June 1990), pp. 80-84	
	C6	IBM Tech. Disc. Bull. "Multiprocessor and Multitasking Architecture for Tool Control of the Advanced via Inspection Tools" (May 1992), pp. 190-191	
	C7	McGeachin, S., "Synthesis and properties of some β-diketiminates derived from acetylacetone, and their metal complexes", Canadian J. of Chemistry, Vol. 46 (1968), pp. 1903-1912	
	C8	Solanki, et al., "Atomic Layer deposition of Copper Seed Layers", Electrochemical and Solid State Letters, 3(10) (2000), pp. 479-480	
	C9	NERAC.COM Retro Search: Atomic Layer Deposition of Copper, dated October 11, 2001	
	C10	NERAC.COM Retro Search: Atomic Layer Deposition / Epitaxy Aluminum Oxide Plasma, dated October 2, 2001	
	C11	NERAC Search abstract of "Atomic Layer deposition of Ta and Ti for Interconnect Diffusion Barriers", by Rossnagel, et al., J. Vac. Sci. & Tech., 18(4) (July 2000)	
	C12	Abstracts of articles re atomic layer deposition	
	C13	Abstracts of search results re atomic layer deposition, search dated January 24, 2002	
	C14	Abstracts of articles re atomic layer deposition and atomic layer nucleation	
	C15	Abstracts of articles re atomic layer deposition and semiconductors and copper	
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	C17	NERAC Search – Atomic Layer Deposition, search dated October 16, 2001	
	C18	Bader, et al., "Integrated Processing Equipment", Solid State Technology, Cowan Pub., Vol. 33, No. 5 (May 1, 1990), pp. 149-154	
	C19	Choi, et al., "The effect of annealing on resistivity of low pressure chemical vapor deposited titanium diboride", J. Appl. Phys. 69(11) (June 1, 1991), pp. 7853-7861	
	C20	Choi, et al., "Stability of TiB <sub>2</sub> as a Diffusion Barrier on Silicon", J. Electrochem. Soc. 138(10) (October 1991), pp. 3062-3067	
	C21	"Cluster Tools for Fabrication of Advanced devices" Jap. J. of Applied Physics, Extended Abstracts, 22 <sup>nd</sup> Conference Solid State Devices and Materials (1990), pp. 849 – 852 XP000178141 (ARTICLE ON ORDER – TO BE PROVIDED)	
	C22	"Applications of Integrated processing", Solid State Technology, US, Cowan Pub., Vol 37, No. 12 (December 1, 1994), pp. 45-47	
	C23	Kitigawa, et al., "Hydrogen-mediated low temperature epitaxy of Si in plasma-enhanced chemical vapor deposition", Applied Surface Science (2000), pp. 30-34 (ARTICLE ON ORDER – TO BE PROVIDED)	
	C24	Lee, et al., "Pulsed nucleation for ultra-high aspect ratio tungsten plugfill", Novellus Systems, Inc. (2001), pp. 1-2 (ARTICLE ON ORDER – TO BE PROVIDED)	
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U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No. 5625/D01/JB		Serial No. 10/731,651	
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	A2	4,389,973	06/28/83	Suntola et al.	118	725	12/11/1981	
	A3	4,413,022	11/01/83	Suntola et al.	427	255.2	06/21/1979	
	A4	4,486,487	12/04/84	Skarp	428	216	04/25/1983	
	A5	4,767,494	08/30/88	Kobayashi et al.	156	606	09/19/1986	
	A6	4,806,321	02/21/89	Nishizawa et al.	422	245	07/21/1985	
	A7	4,829,022	05/09/89	Kobayashi et al.	437	107	12/09/1986	
	A8	4,834,831	05/30/89	Nishizawa et al.	156	611	09/04/1987	
	A9	4,838,983	06/13/89	Schumaker et al.	156	613	03/18/1988	
	A10	4,838,993	06/13/89	Aoki et al.	156	643	12/03/1987	
	A11	4,840,921	06/20/89	Matsumoto	437	89	06/30/1988	
	A12	4,845,049	07/04/89	Sunakawa	437	81	03/28/1988	
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	B2	01/40541 A1	06/07/2001	WO	C23C	16/40	<input checked="" type="checkbox"/>	X
	B3	01/36702 A1	05/25/2001	WO	C23C	16/00	<input checked="" type="checkbox"/>	X
	B4	01/29893 A1	04/26/2001	WO	H01L	21/768	<input checked="" type="checkbox"/>	X
	B5	01/29891 A1	04/26/2001	WO	H01L	21/768	<input checked="" type="checkbox"/>	X
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	C1	Hultman, et al., "Review of the thermal and mechanical stability of TiN-based thin films", <i>Zeitschrift Fur Metallkunde</i> , 90(10) (Oct. 1999), pp. 803-813.						
	C2	Klaus, et al., "Atomic Layer Deposition of SiO <sub>2</sub> Using Catalyzed and Uncatalyzed Self-Limiting Surface Reactions", <i>Surface Review &amp; Letters</i> , 6(3&4) (1999), pp. 435-448.						
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	A15	4,861,417	08/29/89	Mochizuki et al.	156	610	03/24/1988	
	A16	4,876,218	10/24/89	Pessa et al.	437	107	09/26/1988	
	A17	4,927,670	05/22/1990	Erbil	427	255.3	06/22/1988	
	A18	4,931,132	06/05/90	Aspnes et al.	156	601	10/07/1988	
	A19	4,960,720	10/02/90	Shimbo	437	105	08/24/1987	
	A20	4,975,252	12/04/90	Nishizawa et al.	422	245	05/26/1989	
	A21	4,993,357	02/19/91	Scholz	118	715	12/21/1989	
	A22	5,013,683	05/07/91	Petroff et al.	437	110	01/23/1989	
	A23	5,082,798	01/21/92	Arimoto	437	108	09/27/1990	
	A24	5,085,885	02/04/92	Foley et al.	477	38	09/10/1990	
	A25	5,091,320	02/25/92	Aspnes et al.	437	8	06/15/1990	
	A26	5,130,269	07/14/92	Kitahara et al.	437	111	04/25/1989	
A27	5,166,092	11/24/92	Mochizuki et al.	437	105	10/30/1990		
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	B7	01/27347 A1	04/19/2001	WO	C23C	16/44		X
	B8	01/27346 A1	04/19/2001	WO	C23C	16/44		X
	B9	01/15220 A1	03/01/2001	WO	H01L	21/768		X
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*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.						
	C3	Yamaguchi, et al., "Atomic-layer chemical-vapor-deposition of silicon dioxide films with extremely low hydrogen content", <i>Appl. Surf. Sci.</i> , Vol. 130-132 (1998), pp. 202-207.						
	C4	George, et al., "Surface Chemistry for Atomic Layer Growth", <i>J. Phys. Chem.</i> , Vol. 100 (1996), pp. 13121-131.						
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AS	A28	5,225,366	07/06/93	Yoder	437	108	06/22/1990	
	A29	5,246,536	09/21/93	Nishizawa et al.	156	610	03/10/1989	
	A30	5,250,148	10/05/93	Nishizawa et al.	156	611	11/12/1991	
	A31	5,254,207	10/19/93	Nishizawa et al.	156	601	11/30/1992	
	A32	5,256,244	10/26/93	Ackerman	156	613	02/10/1992	
	A33	5,270,247	12/14/93	Sakuma et al.	437	133	07/08/1992	
	A34	5,278,435	01/11/94	Van Hove et al.	257	184	06/08/1992	
	A35	5,281,274	01/25/94	Yoder	118	697	02/04/1993	
	A36	5,290,748	03/01/94	Knuuttila et al.	502	228	07/16/1992	
	A37	5,294,286	03/15/94	Nishizawa et al.	156	610	01/12/1993	
	A38	5,296,403	03/22/94	Nishizawa et al.	437	133	10/23/1992	
	A39	5,300,186	04/05/94	Kitahara et al.	156	613	04/07/1992	
	A40	5,311,055	05/10/94	Goodman et al.	257	593	11/22/1991	
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	B11	00/79019 A1	12/28/2000	WO	C23C	16/00	<input checked="" type="checkbox"/>	X
	B12	00/63957 A1	10/26/2000	WO	H01L	21/205	<input checked="" type="checkbox"/>	X
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AS	C5	George, et al., "Atomic layer controlled deposition of SiO <sub>2</sub> and Al <sub>2</sub> O <sub>3</sub> using ABAB... binary reaction sequence chemistry", <i>Appl. Surf. Sci.</i> , Vol. 82/83 (1994), pp. 460-467.						
AS	C6	Wise, et al., "Diethyldiethoxysilane as a new precursor for SiO <sub>2</sub> growth on silicon", <i>Mat. Res. Soc. Symp. Proc.</i> Vol. 334 (1994), pp. 37-43.						
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	A41	5,316,615	05/31/94	Copel	117	95	03/09/1993	
	A42	5,316,793	05/31/94	Wallace et al.	427	248.1	07/27/1992	
	A43	5,330,610	07/19/94	Eres et al.	117	86	05/28/1993	
	A44	5,336,324	08/09/94	Stall et al.	118	719	12/04/1991	
	A45	5,338,389	08/16/94	Nishizawa et al.	117	89	04/21/1993	
	A46	5,348,911	09/20/94	Jurgensen et al.	117	91	04/26/1993	
	A47	5,374,570	12/20/94	Nasu et al.	437	40	08/19/1993	
	A48	5,395,791	03/07/95	Cheng et al.	437	105	10/20/1993	
	A49	5,438,952	08/08/1995	Otsuka	117	84	01/31/1994	
	A50	5,439,876	08/08/95	Graf et al.	505	447	08/16/1993	
	A51	5,441,703	08/15/95	Jurgensen	422	129	03/29/1994	
	A52	5,443,033	08/22/95	Nishizawa et al.	117	86	03/11/1994	
	A53	5,443,647	08/22/95	Aucoin et al.	118	723 ME	07/11/1994	
	A54	5,455,072	10/03/95	Bension et al.	427	255.7	11/18/1992	
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	B14	00/16377 A2	03/23/2000	WO	H01L	---		X
	B15	00/15881 A2	03/23/2000	WO	C30B	---		X
	B16	00/15865 A1	03/23/2000	WO	C23C	16/00		X
OTHER ART								
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.						
	C7	Niinisto, et al., "Synthesis of oxide thin films and overlayers by atomic layer epitaxy for advanced applications" <i>Mat. Sci. &amp; Eng.</i> , Vol. B41 (1996), pp. 23-29.						
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	A55	5,458,084	10/17/95	Thorne et al.	117	89	12/09/1993	
	A56	5,469,806	11/28/95	Mochizuki et al.	117	97	08/20/1993	
	A57	5,480,818	01/02/96	Matsumoto et al.	437	40	02/09/1993	
	A58	5,483,919	01/16/96	Yokoyama et al.	117	89	08/17/1994	
	A59	5,484,664	01/16/96	Kitahara et al.	428	641	01/21/1994	
	A60	5,503,875	04/02/96	Imai et al.	427	255.3	03/17/1994	
	A61	5,521,126	05/28/96	Okamura et al.	437	235	06/22/1994	
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	A64	5,540,783	07/30/96	Eres et al.	118	725	05/26/1994	
	A65	5,601,651	02/11/97	Watabe	118	715	12/14/1994	
	A66	5,616,181	04/01/97	Yamamoto et al.	118	723 ER	11/21/1995	
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	B17	99/41423 A2	08/19/1999	WO	C23C	---	<input checked="" type="checkbox"/>	X
	B18	99/29924 A1	06/17/1999	WO	C23C	16/04	<input checked="" type="checkbox"/>	X
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	C8	Ritála, et al., "Perfectly conformal TiN and Al <sub>2</sub> O <sub>3</sub> films deposited by atomic layer deposition", <i>Chemical Vapor Deposition</i> , Vol. 5(1) (January 1999), pp. 7-9.						
	C9	Klaus, et al., "Atomically controlled growth of tungsten and tungsten nitride using sequential surface reactions", <i>Appl. Surf. Sci.</i> , Vol 162-163 (2000), pp. 479-491.						
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	A69	5,644,128	07/01/97	Wollnik et al.	250	251	08/25/1994	
	A70	5,693,139	12/02/97	Nishizawa et al.	117	89	06/15/1993	
	A71	5,705,224	01/06/98	Murota et al.	427	248.1	01/31/1995	
	A72	5,707,880	01/13/98	Aftergut et al.	437	3	01/17/1997	
	A73	5,711,811	01/27/98	Suntola et al.	118	711	11/28/1995	
	A74	5,730,802	03/24/98	Ishizumi et al.	118	719	12/27/1996	
	A75	5,747,113	05/05/98	Tsai	427	255.5	07/29/1996	
	A76	5,749,974	05/12/98	Habuka et al.	118	725	07/13/1995	
	A77	5,796,116	08/18/98	Nakata et al.	257	66	07/25/1995	
	A78	5,807,792	09/15/98	Ilg et al.	438	758	12/18/1996	
	A79	5,830,270	11/03/98	McKee et al.	117	106	08/05/1996	
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							YES	NO
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	A82	5,855,675	01/05/99	Doering et al.	118	719	03/03/1997	
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	A87	5,916,365	06/29/99	Sherman	117	92	08/16/1996	
	A88	5,923,056	07/13/99	Lee et al.	257	192	03/12/1998	
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	A90	5,925,574	07/20/99	Aoki et al.	437	31	04/10/1992	
	A91	5,942,040	08/24/99	Kim et al.	118	726	08/27/1997	
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	C19	Bedair, "Atomic layer epitaxy deposition processes", <i>J. Vac. Sci. Technol.</i> 12(1) (Jan/Feb 1994)						
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